

<u>Set Name</u>	<u>Query</u>	<u>Hit Count</u>	<u>Set Name</u>
side by side			result set
	<i>DB=USPT,PGPB,JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=OR</i>		
<u>L20</u>	jp-01023440\$-did.	1	<u>L20</u>
<u>L19</u>	jp-01023440\$-did.	0	<u>L19</u>
<u>L18</u>	jp-64023440\$-did.	0	<u>L18</u>
<u>L17</u>	jp-64023440\$-did.	0	<u>L17</u>
<u>L16</u>	L15 and l14	125	<u>L16</u>
<u>L15</u>	L13 same (resist\$1 or photoresist\$1)	1600	<u>L15</u>
<u>L14</u>	L13 same l4	2114	<u>L14</u>
<u>L13</u>	((narrow\$2 or thinner or small\$4 or differ\$6 or wider or larger) near10 (land\$1 or groove\$1))	123646	<u>L13</u>
<u>L12</u>	L11 and l10	90	<u>L12</u>
<u>L11</u>	L4 same (resist\$1 or photoresist\$1)	2699	<u>L11</u>
<u>L10</u>	L7 same l4	385	<u>L10</u>
<u>L9</u>	L8 same l4	27	<u>L9</u>
<u>L8</u>	L7 same (resist\$1 or photoresist\$1)	294	<u>L8</u>
<u>L7</u>	((narrow\$2 or thinner or small\$4 or differ\$6) near10 (width\$1)) with (land\$1 or groove\$1)	15822	<u>L7</u>
<u>L6</u>	L3 not l5	36	<u>L6</u>
<u>L5</u>	L4 and l3	61	<u>L5</u>
<u>L4</u>	(optical or laser or information) near5 (medium or media or disk\$1 or disc\$1)	343985	<u>L4</u>
<u>L3</u>	L2 same (resist\$1 or photoresist\$1)	97	<u>L3</u>
<u>L2</u>	(pitch or width) same l1	4510	<u>L2</u>
<u>L1</u>	((beam or spot) near5 (size or diameter)) with laser\$1)	24073	<u>L1</u>

END OF SEARCH HISTORY

WEST

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L16: Entry 105 of 125

File: JPAB

Jan 26, 1989

PUB-NO: JP401023440A
DOCUMENT-IDENTIFIER: JP 01023440 A
TITLE: STAMPER

PUBN-DATE: January 26, 1989

INVENTOR-INFORMATION:

NAME

COUNTRY

SUGIMOTO, MAMORU

ASSIGNEE-INFORMATION:

NAME

COUNTRY

SEIKO EPSON CORP

APPL-NO: JP62178417

APPL-DATE: July 17, 1987

INT-CL (IPC): G11B 7/24; G11B 3/70

ABSTRACT:

PURPOSE: To obtain a stamper suitable for forming an optical recording medium with high carrier, low noise and high quality by selecting a groove width of a part (exposed part) of a positive resist coated on a glass master disk to be exposed, developed and removed wider than the groove width of the unexposed part with the resist remained thereupon in manufacturing an optical recording medium substrate.

CONSTITUTION: The process is changed from a conventional process, the numerical aperture of an objective lens 3 is decreased to increase the exposure power. The objective lens 3 is offset and not focused to the resist 2 but placed in out of focus, the development time is extended and the post-bake temperature is raised. Through the constitution above, the resist 2 is deformed before and after the post bake but since the exposed part 1 with a signal written thereupon has a higher exposure power and longer development time, no remained resist exists. The border face of the resist/exposed part to which a ridge of the signal touches is cut sharply in terms of light and the width of the exposed part for signal recording is wide, then the carrier is high. In forming the substrate by using the stamper, the optical recording medium with low noise and high quality is obtained.

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